

*Pro Amick
#11/c*

00862.022168

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Seiji TAKEUCHI et al.

Application No.: 09/819,670

Filed: March 29, 2001

For: STOCKER, EXPOSURE APPARATUS,
DEVICE MANUFACTURING METHOD,
SEMICONDUCTOR MANUFACTURING
FACTORY, AND EXPOSURE APPARATUS :
MAINTENANCE METHOD)

)
: Examiner: A. Kosowski
)
: Group Art Unit: 2125
)
: Confirmation No.: 3161
)
:
) September 23, 2003
:
)

Mail Stop RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

RECEIVED

SEP 25 2003

Technology Center 2100

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application
as follows: